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## In the claims:

Claims 6 and 16 are canceled. Claims 4 and 17 are amended. Claim 21-26 are added.

1. (Original) A carrier head for chemical mechanical polishing of a substrate, comprising:

a base; and

- a flexible membrane extending beneath the base to define a chamber and provide a mounting surface against which a substrate may be positioned, the mounting surface including a low adhesive material to which the substrate does not readily adhere.
- 2. (Original) A carrier head for chemical mechanical polishing of a substrate. comprising:

a base, and

- a flexible membrane extending beneath the base to define a chamber, the flexible membrane including a core of a first material and an outer layer of a second material having a lower adhesion to the substrate than the first material, an exposed surface of the outer layer providing a mounting surface for the substrate.
- (Original) The carrier head of claim 2, wherein the first material is an elastomer 3. and the second material is a polymer.
- (Currently Amended) The carrier head of claim 2, wherein a thickness of the outer layer is between about  $0.1 \ 0.4$  and  $2.0 \ 0.7$  microns.
- 5. (Original) The carrier head of claim 2 wherein a coefficient of friction of the mounting surface against the substrate is less than about .5.
  - 6. (Canceled)

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7. (Original) The carrier head of claim 2, wherein the second material is deposited on the first material.

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- 8. (Original) The carrier head of claim 7, wherein the second material is deposited on the first material by gas phase polymerization coating.
- 9. (Original) The carrier head of claim 2, wherein the second material is deposited on selected portions of the first material to form a pattern.
- 10. (Original) A carrier head for chemical mechanical polishing of a substrate, comprising:
  - a base; and
- a flexible membrane extending beneath the base to define a chamber, the flexible membrane including an inner portion formed of a first material and an outer portion formed of a second material, the outer portion providing a mounting surface against which a substrate may be positioned and the second material having a lower adhesion to the substrate than the first material.
  - 11. (Original) A flexible membrane for a carrier head, comprising: a core of a first material; and

an outer layer of a second material formed over the core, an exposed surface of the outer layer providing a mounting surface for a substrate, the second material having a lower adhesion to the substrate than the first material.

12. (Original) A method of moving a substrate with a carrier head, comprising: positioning a substrate against a mounting surface of a flexible membrane of a carrier head, the flexible membrane defining a pressurizable chamber within the carrier head, the flexible membrane including a low adhesion material to which the substrate does not readily adhere;

evacuating the chamber to form a seal between the mounting surface and the substrate;

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placing the substrate on a receiving surface; and

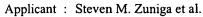
pressurizing the chamber to break the seal between the substrate and the mounting surface.

13. (Original) A method of making a flexible membrane for a carrier head, comprising:

providing a core formed of a first material;

depositing a second material onto the core to form a layer, the layer providing a mounting surface for a substrate, the second material having a lower adhesion to the substrate than the first material.

- 14. (Original) The method of claim 13, wherein the providing step includes providing a core formed of an elastomer.
- 15. (Original) The method of claim 13, wherein the depositing step includes depositing polymer.
  - 16. (Canceled)
- (Currently Amended) The method of claim 13, wherein the depositing step forms the layer with a thickness between about 0.1 0.4 and 2.0 0.7 microns.
  - 18. (Original) The method of claim 13, wherein the depositing step forms the layer with coefficient of friction against the substrate less than about .5.
  - 19. (Original) The method of claim 13, wherein the depositing step includes gas phase polymerization coating.
  - 20. (Original) The method of claim 13, wherein the depositing step forms the layer on selected portions of the first material to form a pattern.



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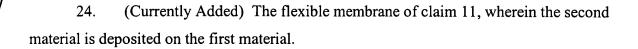
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21. (Currently Added) The flexible membrane of claim 11, wherein the first material is an elastomer and the second material is a polymer.

- 22. (Currently Added) The flexible membrane of claim 11, wherein a thickness of the outer layer is between about 0.4 and 0.7 microns.
- 23. (Currently Added) The flexible membrane of claim 11, wherein a coefficient of friction of the mounting surface against the substrate is less than about .5.



- 25. (Currently Added) The flexible membrane of claim 24,wherein the second material is deposited on the first material by gas phase polymerization coating.
- 26. (Currently Added) The flexible membrane of claim 11, wherein the second material is deposited on selected portions of the first material to form a pattern.